



National Accreditation Board for
Testing and Calibration Laboratories

CERTIFICATE OF ACCREDITATION

BNN COMMUNICATION ENGINEERS PVT.LTD. (EMR DIV)

has been assessed and accredited in accordance with the standard

ISO/IEC 17025:2017

**"General Requirements for the Competence of Testing &
Calibration Laboratories"**

for its facilities at

33/33, INDUSTRIAL AREA, SITE 2, LONI ROAD, MOHAN NAGAR, SAHIBABAD, GHAZIABAD, UTTAR
PRADESH, INDIA

in the field of

TESTING

Certificate Number: TC-8196

Issue Date: 08/09/2022

Valid Until:

07/09/2024

This certificate remains valid for the Scope of Accreditation as specified in the annexure subject to continued satisfactory compliance to the above standard & the relevant requirements of NABL.
(To see the scope of accreditation of this laboratory, you may also visit NABL website www.nabl-india.org)

Name of Legal Entity: BNN COMMUNICATION ENGINEERS PRIVATE LIMITED

Signed for and on behalf of NABL



N. Venkateswaran
Chief Executive Officer



National Accreditation Board for Testing and Calibration Laboratories

SCOPE OF ACCREDITATION

Laboratory Name : BNN COMMUNICATION ENGINEERS PVT.LTD. (EMR DIV), 33/33, INDUSTRIAL AREA, SITE 2, LONI ROAD, MOHAN NAGAR, SAHIBABAD, GHAZIABAD, UTTAR PRADESH, INDIA

Accreditation Standard ISO/IEC 17025:2017

Certificate Number TC-8196 **Page No** 1 of 2

Validity 08/09/2022 to 07/09/2024 **Last Amended on** 16/10/2023

S.No	Discipline / Group	Materials or Products tested	Component, parameter or characteristic tested / Specific Test Performed / Tests or type of tests performed	Test Method Specification against which tests are performed and / or the techniques / equipment used
Site Facility				
1	ELECTRONICS- EMC TEST FACILITY	Fully Anechoic Chamber	Free Space Normalised Site Attenuation (FSNSA) FAR Configuration	CISPR 16-1-4+AMD1+AMD2:2023
2	ELECTRONICS- EMC TEST FACILITY	Fully Anechoic Chamber/Semi Anechoic Chamber / Open Area Test Site	Field Uniformity	IEC 61000-4-3:2020
3	ELECTRONICS- EMC TEST FACILITY	Fully Anechoic Chamber/Semi Anechoic Chamber / Open Area Test Site	Site Voltage Standing Wave Ratio (sVSWR)	CISPR 16-1-4, Edition 3.0 (Withdrawn):2010
4	ELECTRONICS- EMC TEST FACILITY	Fully Anechoic Chamber/Semi Anechoic Chamber / Open Area Test Site	Site Voltage Standing Wave Ratio (sVSWR)	CISPR 16-1-4+AMD1:2020
5	ELECTRONICS- EMC TEST FACILITY	Fully Anechoic Chamber/Semi Anechoic Chamber / Open Area Test Site	Field Uniformity	IEC 61000-4-3:2020
6	ELECTRONICS- EMC TEST FACILITY	Fully Anechoic Chamber/Semi Anechoic Chamber / Open Area Test Site	Site Voltage Standing Wave Ratio (sVSWR)	CISPR 16-1-4 +AMD1:2020
7	ELECTRONICS- EMC TEST FACILITY	Semi Anechoic Chamber with Ground Plane/Open Area Test Site	ALSE performance validation using Long Wire Antenna Method	IEC/CISPR 25, Edition 5.0 (Annexure I):2021
8	ELECTRONICS- EMC TEST FACILITY	Semi Anechoic Chamber / Open Area Test Site with ground Plane	Normalised Site Attenuation	ANSI C63.4:2014
9	ELECTRONICS- EMC TEST FACILITY	Semi Anechoic Chamber / Open Area Test Site with ground Plane	Normalised Site Attenuation	ANSI C63.4:2014
10	ELECTRONICS- EMC TEST FACILITY	Semi Anechoic Chamber / Open Area Test Site with ground Plane	Normalised Site Attenuation	ANSI C63.4A (Amendment):2017
11	ELECTRONICS- EMC TEST FACILITY	Semi Anechoic Chamber / Open Area Test Site with ground Plane	Normalised Site Attenuation	ANSI C63.4A:2017
12	ELECTRONICS- EMC TEST FACILITY	Semi Anechoic Chamber / Open Area Test Site with ground Plane	Normalised Site Attenuation	CISPR 16-1-4+AMD1:2020
13	ELECTRONICS- EMC TEST FACILITY	Semi Anechoic Chamber / Open Area Test Site with ground Plane	Normalised Site Attenuation	CISPR 16-1-4+AMD1:2020
14	ELECTRONICS- EMC TEST FACILITY	Semi Anechoic Chamber / Open Area Test Site with ground Plane	NSIL (Normalised Site insertion loss measurement)	CISPR 16-1-4+AMD1+AMD2:2023
15	ELECTRONICS- EMC TEST FACILITY	Semi Anechoic Chamber with Ground Plane/Open Area Test Site	ALSE performance validation using Long Wire Antenna Method	IEC/CISPR 25 (Annexure I):2021
16	ELECTRONICS- EMC TEST FACILITY	Semi or Fully Anechoic Chamber/Open Area Test Site	Setup Table Influence (STI) Measurement	CISPR 16-1-4+AMD1+AMD2:2023
17	ELECTRONICS- EMC TEST FACILITY	Shielded Chamber/ Enclosure/ Room	Shielding Effectiveness	BS EN 50147-1:1997



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LONI ROAD, MOHAN NAGAR, SAHIBABAD, GHAZIABAD, UTTAR PRADESH, INDIA

Accreditation Standard

ISO/IEC 17025:2017

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18	ELECTRONICS- EMC TEST FACILITY	Shielded Chamber/ Enclosure/ Room	Shielding Effectiveness	IEEE 299:2006
19	ELECTRONICS- EMC TEST FACILITY	Shielded Chamber/ Enclosure/ Room	Shielding Effectiveness	IEEE 299:2006
20	ELECTRONICS- EMC TEST FACILITY	Shielded Chamber/ Enclosure/ Room	Shielding Effectiveness	MIL STD 188-125.1 (Appendix A):2005
21	ELECTRONICS- EMC TEST FACILITY	Shielded Chamber/ Enclosure/ Room	Shielding Effectiveness	MIL STD 188-125.2, (Appendix A):2005
22	ELECTRONICS- EMC TEST FACILITY	Shielded Chamber/ Enclosure/ Room	Shielding Effectiveness	MIL Std. 188-125.1,(Appendix A):2005
23	ELECTRONICS- EMC TEST FACILITY	Shielded Chamber/ Enclosure/ Room	Shielding Effectiveness	MIL Std. 188-125.2,(Appendix A):2005
24	ELECTRONICS- EMC TEST FACILITY	Shielded Enclosure/Cabinet	Shielding Effectiveness	IEC 61000-5-7:2001
25	ELECTRONICS- EMC TEST FACILITY	Shielded Enclosure/Cabinet	Shielding Effectiveness	IEC 61000-5-7:2001
26	ELECTRONICS- EMC TEST FACILITY	Shielded Enclosure/Cabinet (0.75 m to 2 m)	Shielding Effectiveness	IEEE 299.1:2013
27	ELECTRONICS- EMC TEST FACILITY	Shielded Enclosure/Cabinet (0.75 m to 2 m)	Shielding Effectiveness	IEEE 299.1:2013